

In the Specification:

Please amend the paragraph at page 27, line 27 through page 28, line 8 as set forth below:

When the cover ~~101~~ 130 and the substrate support rods 102 are in the upper positions as shown in the left half part of FIG. 12, the wafer carrying arm 14a (FIG. 1) of the main wafer conveyer 14 carries a wafer W to a position above the substrate support rods 102, and then lowers. Thereby, the wafer W is carried by the arm 14a is transferred to the support pins 105 of the substrate support rods 102. Then, the arm 14a is moved horizontally away from a position above the vessel body 100. A locking mechanism 140 is provided for preventing the accidental fall of the cover 130 and the resulting collision of the cover 130 against the substrate carrying arm 14a, the substrate support rods 102 and the wafer lying under the cover 130 due to an unexpected air down (i.e., the failure in the air supply system for supplying working air to the pneumatic cylinder actuator 134). The locking mechanism 140 includes a locking pin 141, namely, a stopper, and an actuator 142 for horizontally moving the locking pin 141. The stopper in 141 is advanced into a space under the cover support member 133 to restrain the cover 130 from falling down.